

Title (en)
DEVICE AND METHOD FOR MANUFACTURING A PARTICULATE FILTER WITH REGULARLY SPACED MICROPORES

Title (de)
VORRICHTUNG UND VERFAHREN ZUR HERSTELLUNG EINES PARTIKELFILTERS MIT GLEICHMÄSSIG VERTEILTEN MIKROPOREN

Title (fr)
DISPOSITIF ET PROCÉDÉ DE FABRICATION D'UN FILTRE À PARTICULES COMPORTANT DES MICROPORES ESPACÉS RÉGULIÈREMENT

Publication
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Application
EP 08743851 A 20080313

Priority

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- US 85661507 A 20070917

Abstract (en)
[origin: WO2008112888A1] Various embodiments disclose devices and methods for fabricating microporous particulate filters with regularly spaced pores wherein sheet membrane substrates are exposed to energetic particle radiation through a mask and the damaged regions removed in a suitable developer. The required depth of field is achieved by using energetic particles to minimize diffraction and an energetic particle source with suitably small diameter.

IPC 8 full level
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Citation (search report)

- [XDI] HAN K ET AL: "Fabrication and characterization of polymeric microfiltration membranes using aperture array lithography", JOURNAL OF MEMBRANE SCIENCE, ELSEVIER SCIENTIFIC PUBL.COMPANY. AMSTERDAM, NL, vol. 249, no. 1-2, 1 March 2005 (2005-03-01), pages 193 - 206, XP004731307, ISSN: 0376-7388, DOI: 10.1016/J.MEMSCI.2004.09.044
- [X] HUDEK P ET AL: "Directly sputtered stress-compensated carbon protective layer for silicon stencil masks*", JOURNAL OF VACUUM SCIENCE & TECHNOLOGY B: MICROELECTRONICSPROCESSING AND PHENOMENA, AMERICAN VACUUM SOCIETY, NEW YORK, NY, US, vol. 17, no. 6, 1 November 1999 (1999-11-01), pages 3127 - 3131, XP012007889, ISSN: 0734-211X, DOI: 10.1116/1.590966
- See also references of WO 2008112888A1

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